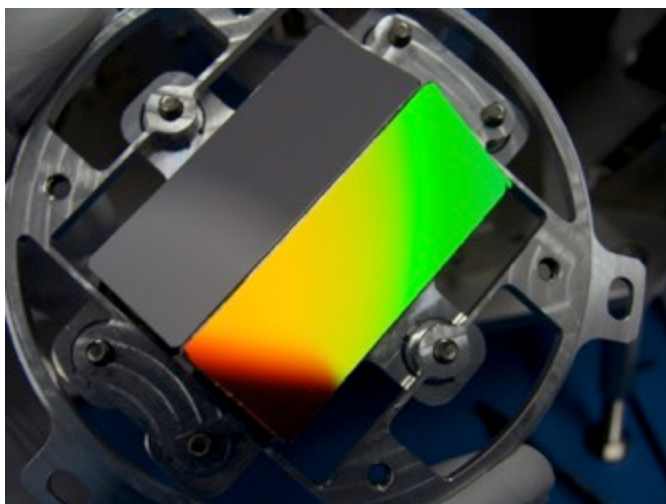
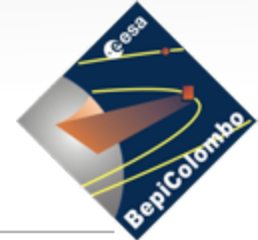




PHEBUS

Probing of Hermean Exosphere by UV Spectroscopy



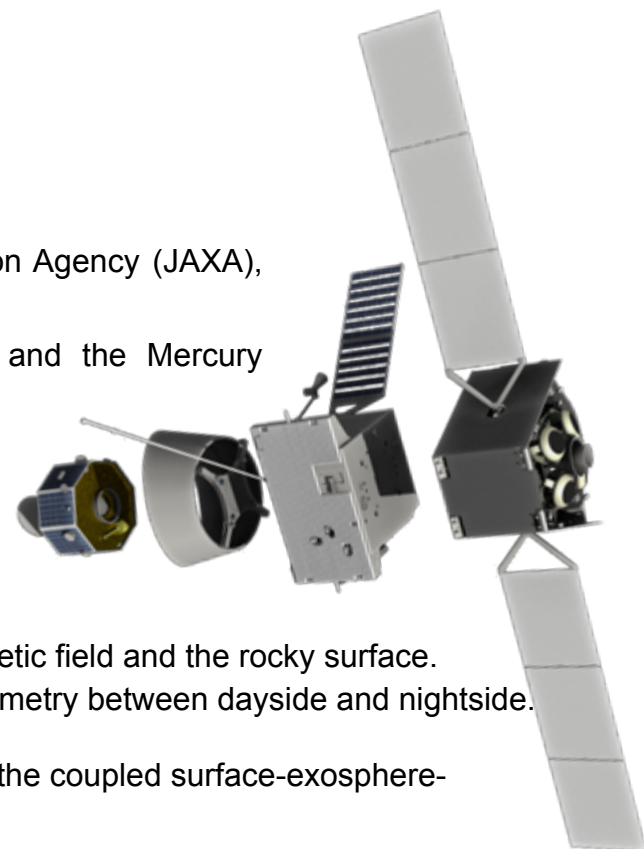
DESIGN
CALIBRATION
EXPERIENCE FEEDBACK

Jean-François MARISCAL
CNRS/LATMOS
mariscal@latmos.ipsl.fr



Mission

- BepiColombo is the first European mission toward Mercury.
- Cornerstone mission of the ESA Cosmic Vision program.
- BepiColombo is a joint mission between ESA and the Japan Aerospace Exploration Agency (JAXA), executed under ESA leadership.
- The mission comprises two spacecraft: the Mercury Planetary Orbiter (MPO) and the Mercury Magnetospheric Orbiter (MMO).



PHEBUS: Scientific objectives

- The exosphere of Mercury is very tenuous, with a pressure of a fraction of picobar.
- The exosphere results from a complex interplay of the solar wind, the planetary magnetic field and the rocky surface.
- The exosphere is highly variable with time and space, characterized by a global asymmetry between dayside and nightside.

The core scientific objectives of PHEBUS are oriented toward a better understanding of the coupled surface-exosphere-magnetosphere system. The main measurement objectives are the following:

- To detect new species, including metallic species (Si, Mg, Fe, ...), atoms (C, N, S, ...), molecules and radicals (H₂O, H₂, OH, CO), noble gases (Ar, Ne), ions (He⁺, Na⁺, Mg⁺, ...), in addition to already detected species (Na, K, Ca, O, H, He).
- To measure an average exosphere (densities of constituents, vertical structure), with as much as possible species monitored together, at different positions of Mercury around the Sun.
- To measure sharp local and temporal variations of the exosphere content, at specific times and places of interest.
- To search for albedo variations of Mercury's nightside surface, lighted by the interplanetary H Ly- α glow, at 121.6 nm, in order to exhibit possible signatures of surface ice layers (H₂O, SO₂, N₂, CO₂, ...) in high latitude polar craters.

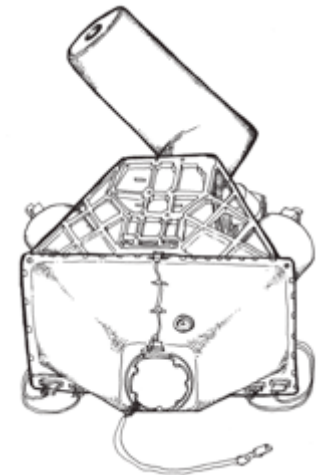


CONTEXT : The PHEBUS Project

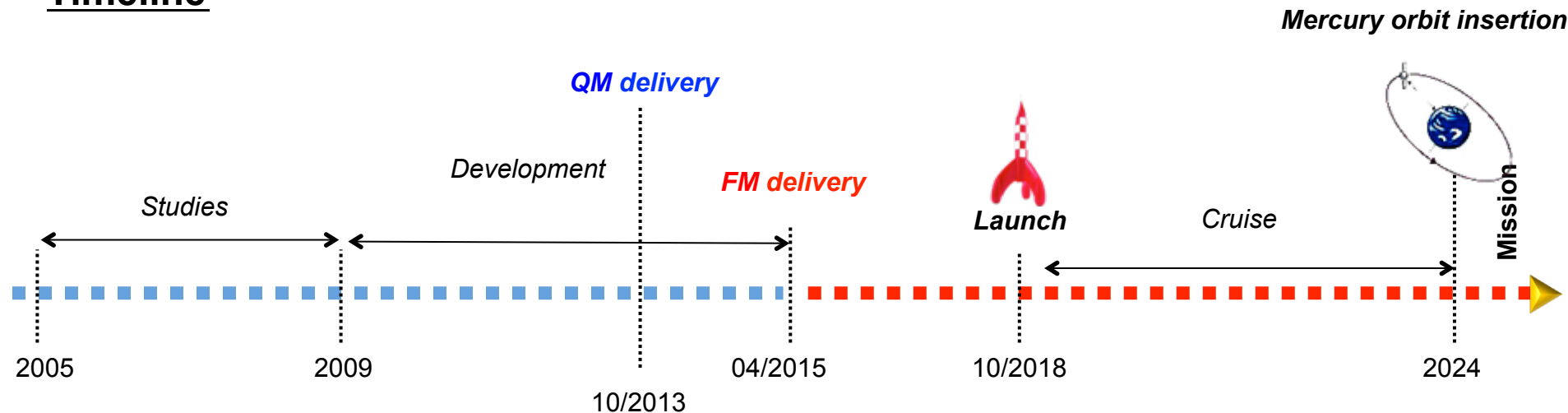


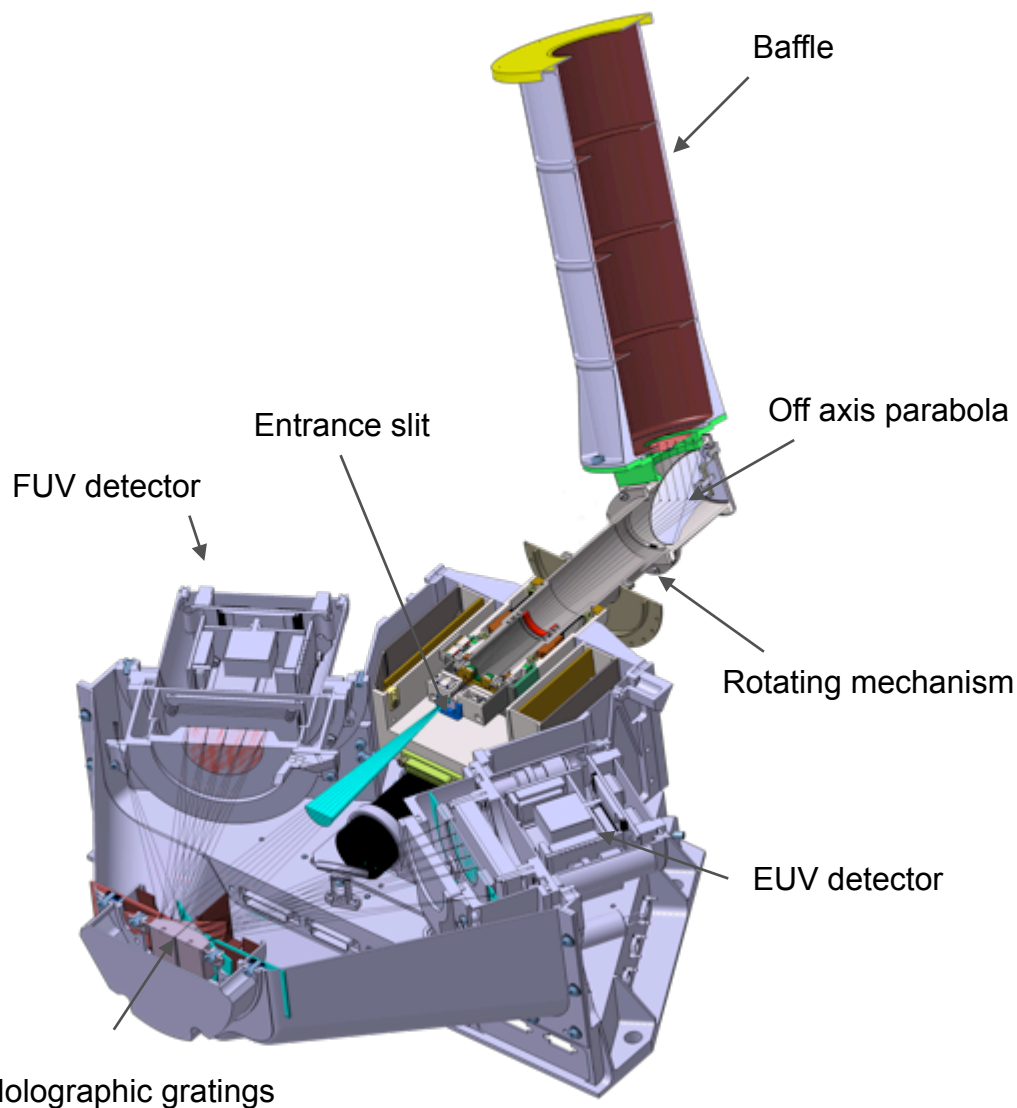
French-led instrument with international cooperation

- PHEBUS: The only French PI-Ship instrument on board MPO.
- LATMOS/CNRS : Project leadership.
- CNES : Prime contractor ship of the French contribution.
- International cooperation:
 - Japan – Tokyo University (I. Yoshikawa): FUV/EUV detectors supplier.
 - Russia - IKI (O. Korablev) : Pointing mechanism supplier.
 - Italy - LUXOR Lab, Padova University (M.G. Pelizzo): Optical calibrations.



Timeline





PHEBUS Spectrometer – Schematic view

Spectral range	EUV : 55 nm - 155 nm FUV: 145 nm – 315 nm NUV lines: 404.7 nm & 422.8 nm
Spectral resolution	EUV : 0.5 nm FWHM FUV : 0.8 nm FWHM
f number	f/# = 6.7
Paraxial FOV	2° x 0.1°
Detection mode	Counting mode
Sensitivity	0.1 ct.s ⁻¹ .R ⁻¹
Guard angle	± 8.3° (attenuation > 10 ⁷)

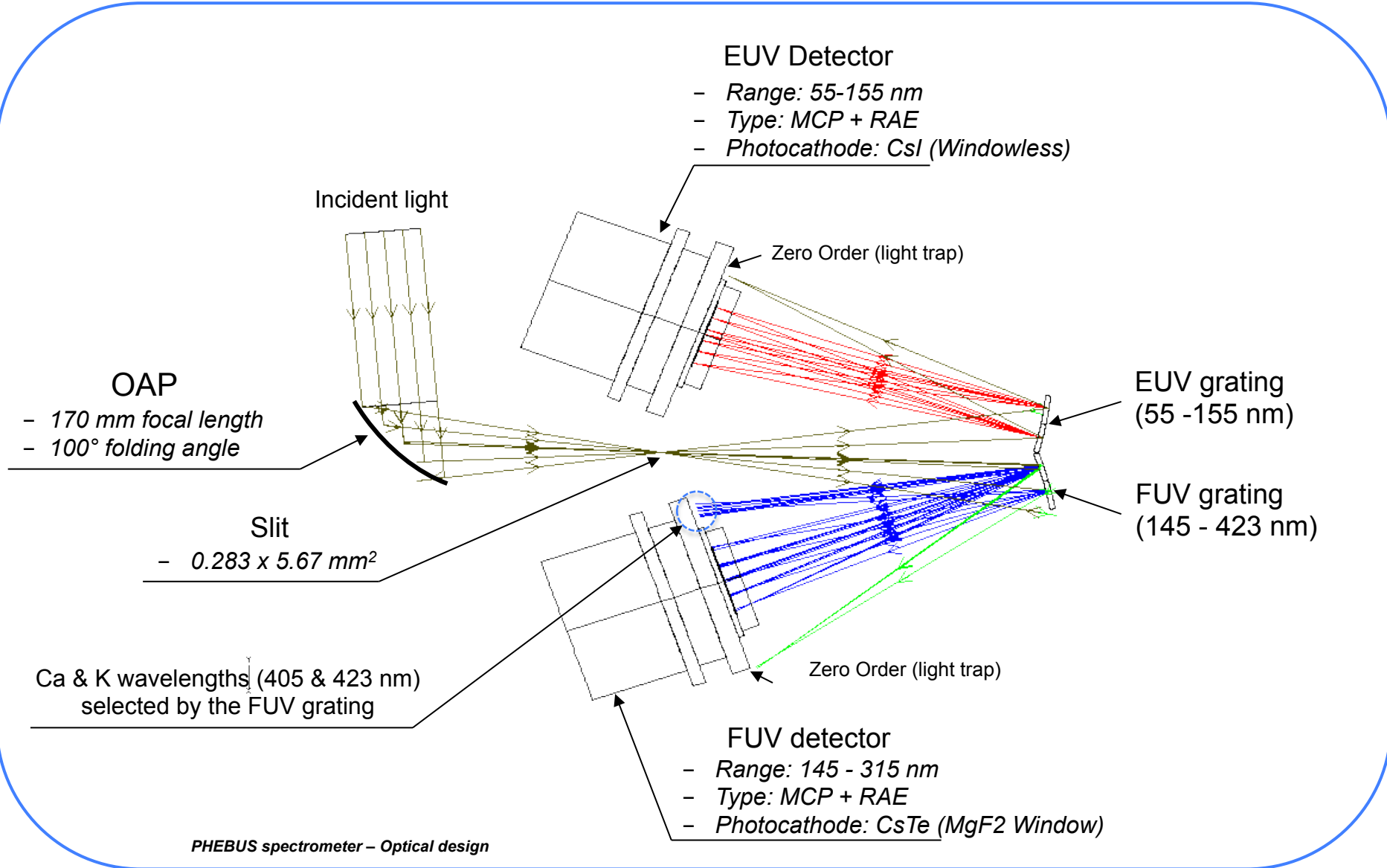
Performances de l'instrument

Dimensions	500 x 400 x 400 mm ³
Weight	7.5 kg
Electric consumption	25 W (max)

Caractéristiques dimensionnelles



OPTICAL DESIGN



PHEBUS spectrometer – Optical design

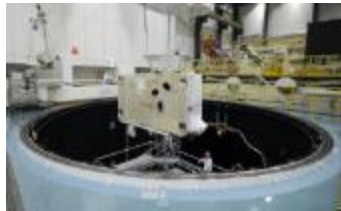


5 models

2009
Optical Prototype



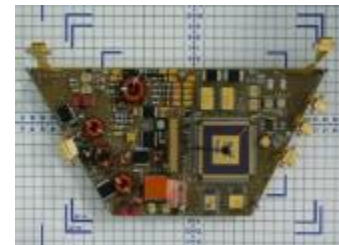
2010
Structural & thermal Model



2011
Electrical Model



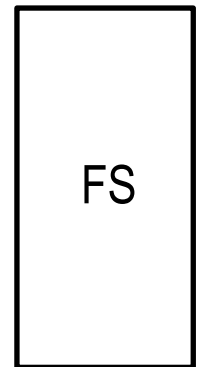
2012 >> 2013
Qualification Model



2013 >> 2015
Flight Model



May 2015 >> 2017
Flight Spare



TELESCOPE

- Entrance baffle

Objectives :

- Prevent direct illumination of the entrance mirror by a bright source located outside the guard angle ($\sim 8^\circ$)
- Attenuate the diffused light inside the baffle with multi-reflections before reaching the mirror
- Specification : Attenuation of 10^8 outside guard angle

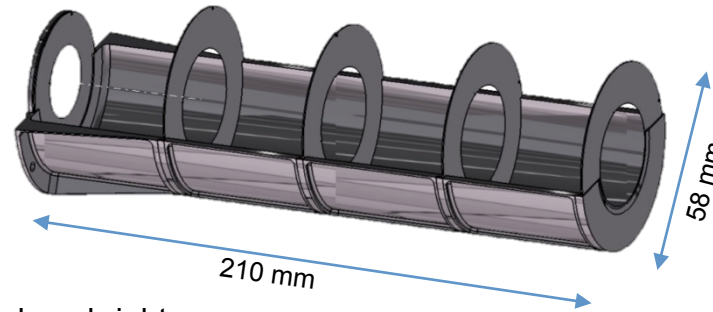
Design guidelines (to apply to any surface inside the baffle):

- Surface is not seen from the slit.
- OR: surface is not illuminated by direct light

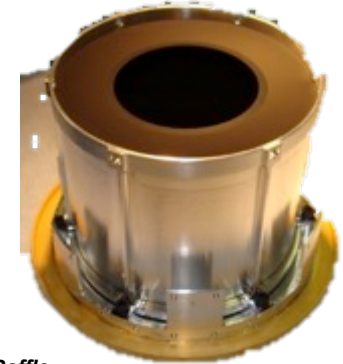
Design:

- Cylindrical body with 4 stages / 5 diaphragms, including entrance pupil.
- Screwed aluminium assembly.
- Minimum of 2 diffuse reflections on the surfaces (geometry).
- Only 1 diffuse reflection on the edges (geometry).
- Black diffuse coating on surfaces : TIS $\sim 1\%$ (« Magic black » Acktar).
- Edges as thin as possible, also covered with black coating ($R_c < 5 \mu\text{m}$).

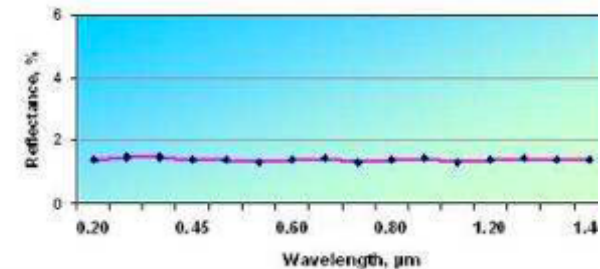
Poids : 170g



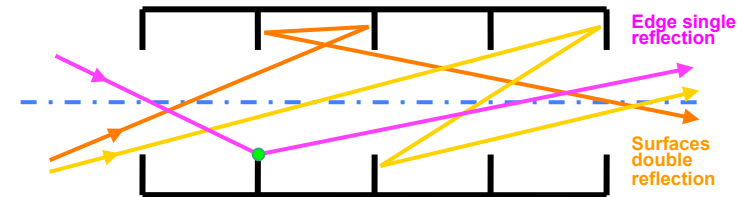
PHEBUS Entrance Baffle



Hemispherical Reflectance



« Magic Black » Reflectance



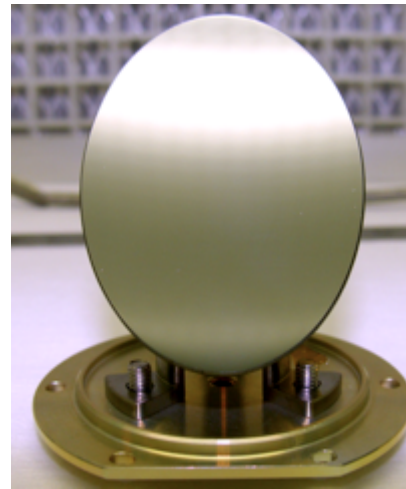
Multi reflection example

TELESCOPE

- Off axis parabola

Characteristics :

- $f' = 170$ mm.
- 100° folding angle – $\phi = 50$ mm.
- Sintered SiC + SiC CVD (thickness~ 400 μm).
- Super polishing : roughness < 0.7 nm RMS.
- Shape error: SFE = 190 nm.



Off axis parabola

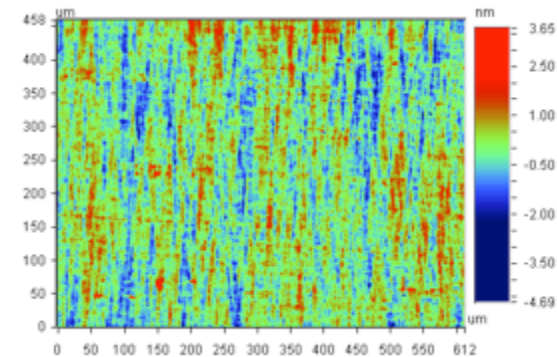
Justification of the Silicon Carbide choice :

- UV reflectivity.
- Thermal and mechanical properties (Low CTE, high thermal conductivity).

Manufacturing steps and industrial scheme:

1. Sintered SiC substrate manufacturing: *Boostec (France)*.
2. Rough machining & grinding (shape tolerance 3 μm PV): *Nanoshape (Belgium)*.
3. CVD preparation (surface roughness ~ 0.2 μm) : *AMOS (Belgium)*
4. CVD: *Schunk*.
5. Dye penetrant inspection: *AMOS*
6. Fine grinding and polishing down to 1nm of RMS roughness: *AMOS*
7. Correction of shape error by ion etching: *AMOS*

AMOS



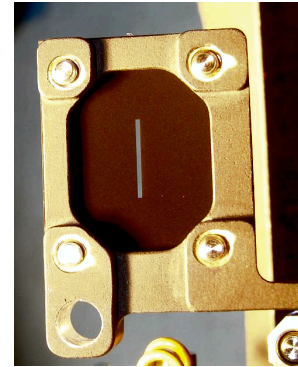
Roughness measurement

SPECTROMETER

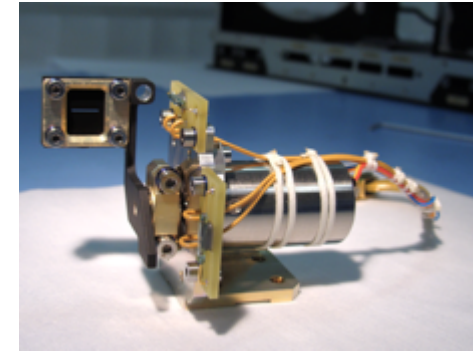
- Entrance slit

Characteristics:

- Nickel electroforming (0.283 x 5.67 mm²).
- CuO black coating.
- Movable mechanism (star calibration).



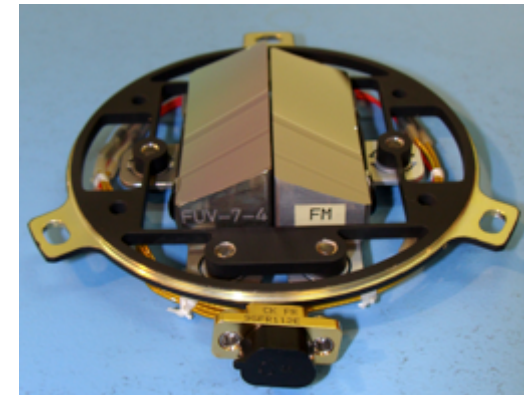
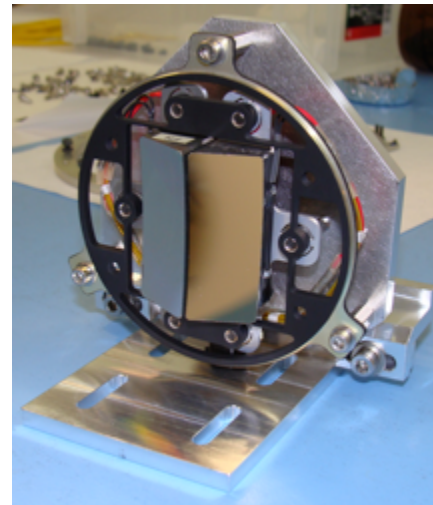
Entrance slit



- Diffraction gratings (*Horiba JobinYvon*)

Type	Holographic (aberrations corrected)
Shape	Spherical (R = 173.55 mm)
Materials	Substrate : Aluminium 7075 Reflective coating : + Pt coating
Groove profile	Laminar ion-etched
Groove density	EUV grating : 2726 gr/mm FUV grating : 1603 gr/mm
Size	14 x 44 mm ²

Characteristics



Holographic gratings

Detectors

- Mode: photon counting.
- Technology : Micro Channel Plate (MCP) + Resistive Anode Encoder (RAE).
- Gain : $\sim 2 \times 10^7$.

Dimensions: active area is $40 \times 25 \text{ mm}^2$, equivalent to a matrix of 1024×512 virtual pixels (spectral x spatial).

Advantages :

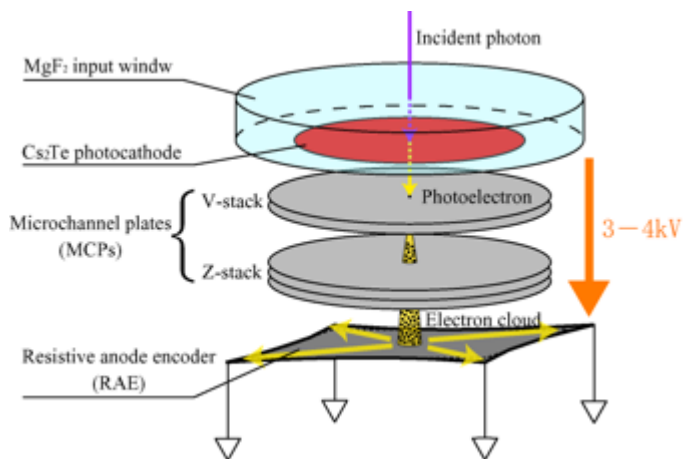
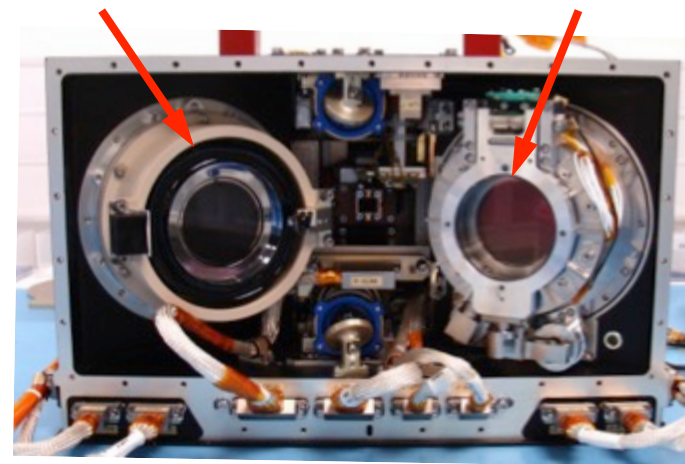
- Very high sensitivity mainly due to a very low dark current : $< 1 \text{ ct/s/cm}^2$ (from -20°C to 40°C)
- No cooling system => avoid mass and power expensive devices

FUV detector

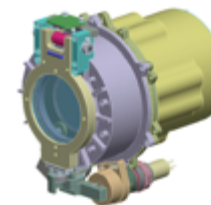
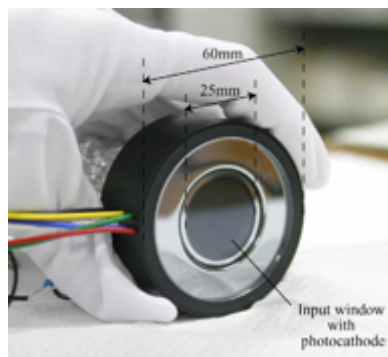
- 145 - 315 nm
- Photocathode CsTe
- Window MgF_2

EUC detector

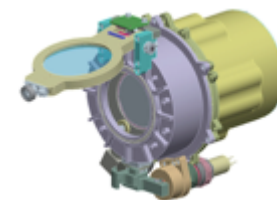
- 55 - 155 nm
- Photocathode CsI
- Windowless



MCP+RAE schematic diagram



EUV detector : closed window

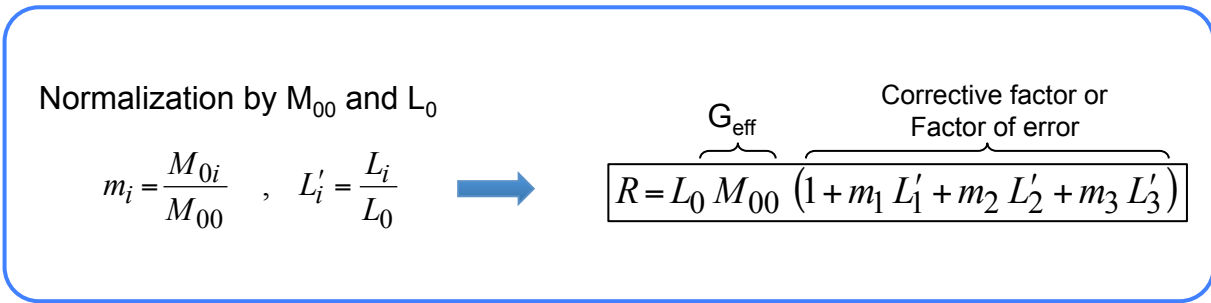
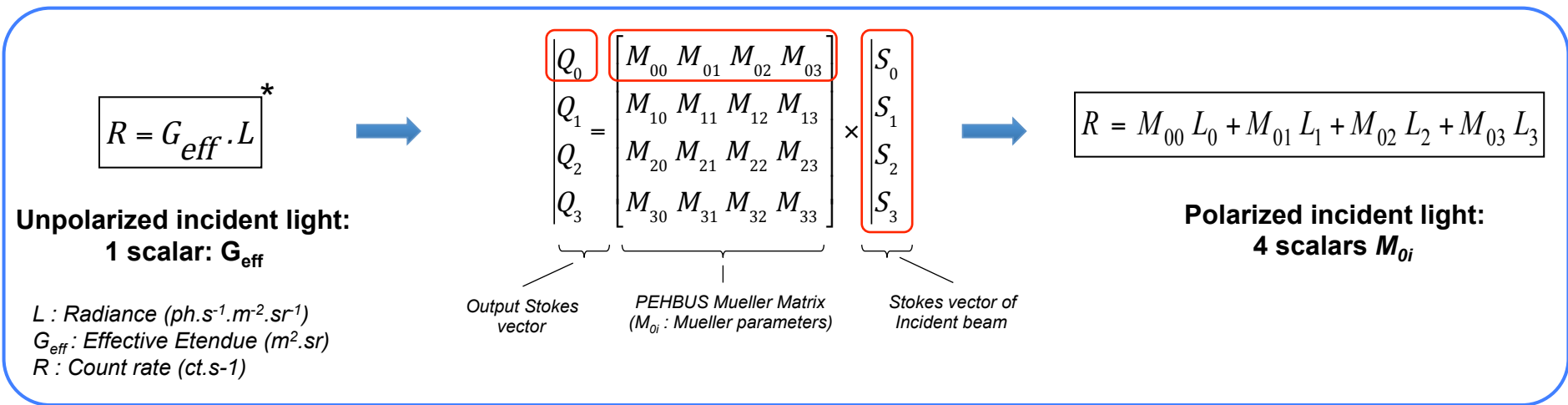


EUV detector: open window

Specific effort was done for the calibration activities

⇒ To know the instrument response and behaviour as precisely as possible

- A precise calibration is essential to process relevant scientific data.
- We put forward a theoretical calibration plan as complete as possible.
- The link between what we measure (the count rate R) and what we want to know (the radiance L) is the main purpose of the calibration.



- We must know, a priori, the polarization state of the source !!
- If we only know the fraction of incident light which is polarized, we can estimate an upper bound of the error factor.

* in the linear working range



- Calibration plan conclusion

System

Geometric

- Etendue G
 - FOV
- Solid angle Ω

Radiometric

- Effective Etendue G_{eff}
- Effective area S_{eff}
- Mueller parameters M

Spectral

- ISRF
- PSF

Sub-Systems

Radiometric

- Mirror reflectivity
- Grating efficiency
- Baffle attenuation

- From theory to practice

The calibration plan has been translated into technical specifications

Division of calibration activities into work packages (~20):

- Description of experimental methods: How to measure ?.
- Description of the experiment: Optical Ground System Equipment (OGSE).





Experimental constraints

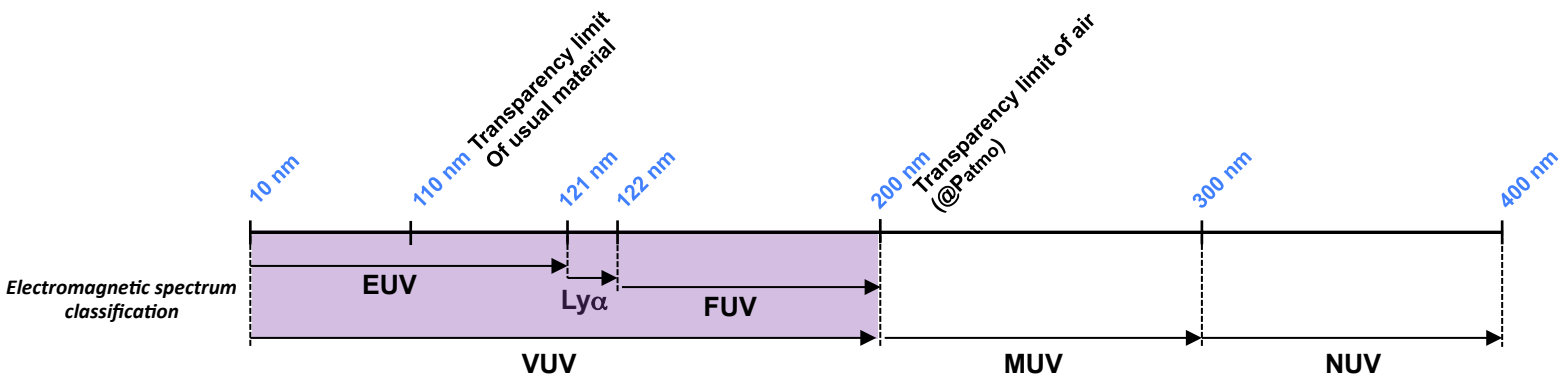
- Wide spectral range : from 55 nm to 423 nm

Requirements:

- Wide variety of sources, sensors and optical components.
- Well known OGSE (absolute calibration)

- Vacuum optics

- To reach wavelengths < 200 nm \Rightarrow Need to be under vacuum (ambient air transparency limit).
 - Instrument accessibility is made difficult (alignments ☹).
 - Electrical feedthroughs.
- To reach wavelengths < 110 nm \Rightarrow material transparency limits ☹.
 - The use of mirror at grazing incidence.
 - The use of diffuser is made not possible (how to make an extended source?).
 - Windowless sources and detectors.



EUUV : Extrem Ultra-Violet
FUV : Far Ultra-Violet
VUV : Vacuum Ultra-Violet
MUV : Middle Ultra-Violet
NUV : Near Ultra-Violet



Example : Vacuum optical bench

Goals

- To carry out spectral and radiometric calibrations.
- To enable calibrations of optical subsystems by measuring either the reflectivity (optical mirrors), the transmission (filters, windows) or the efficiency (gratings) in VUV.

Main features

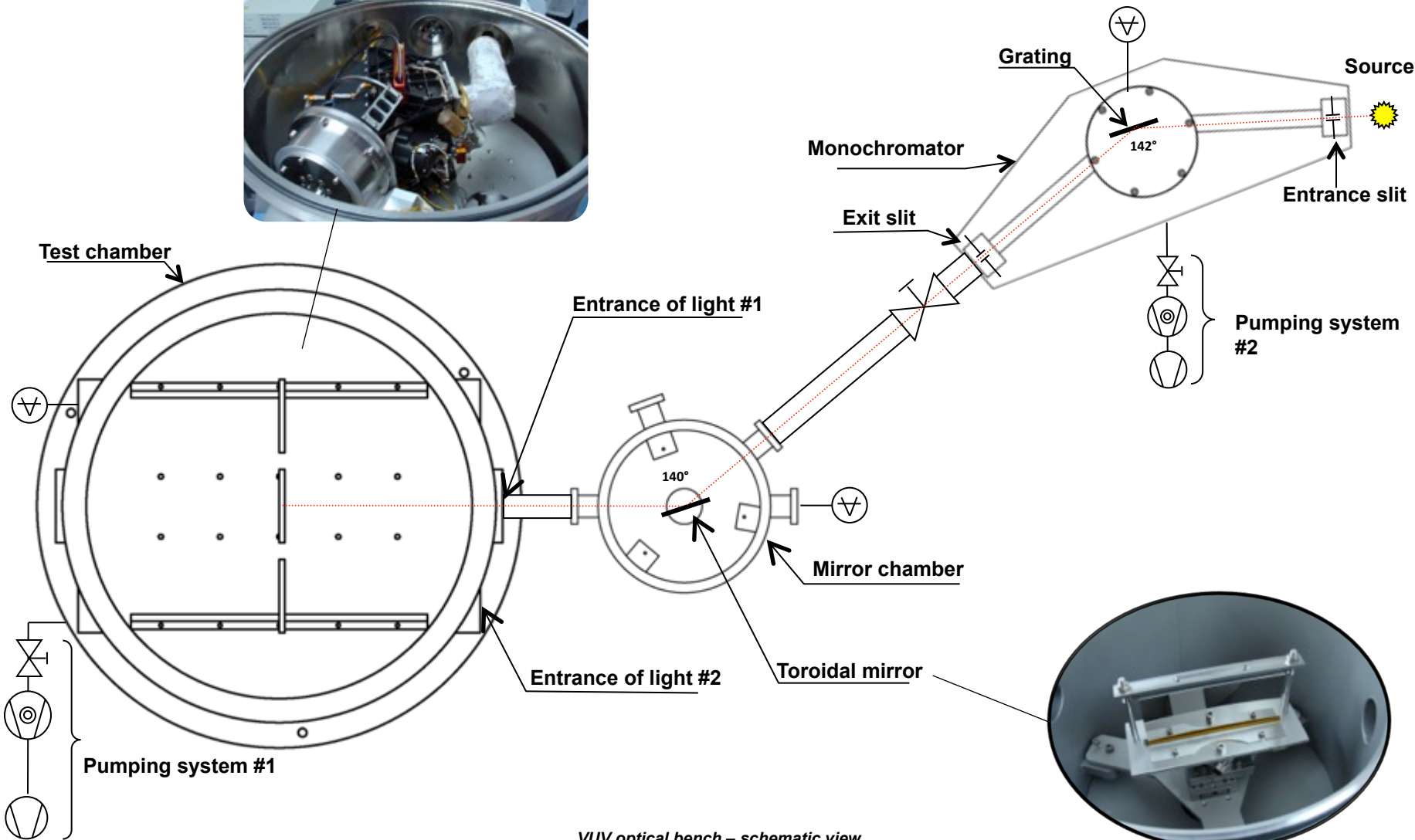
- Spectral range: 30 – 200 nm (2 gratings).
- Spectral resolution < 1 nm.
- 2 operating modes : focused or collimated beam.
- Available sources:
 - Pen Ray (Hg, Zn/Cd).
 - Deuterium lamp (Hamamatsu *L10366 series*).
 - RF flow lamp windowless (He, Ne, N₂, Ar, O, H).
- Available detectors:
 - Channel Electron Multiplier (Amptektron MD-502).
 - Photomultiplier (Hamamatsu R6835P).
- Vacuum tank: 250 L – Min pressure = 10⁻⁶ mbar.
- Automated system:
 - Pumping operations.
 - Remote control & monitoring.
 - Safety device to protect sample/instrument under vacuum.
 - Alarm operating anomalies (notifications sent by e-mails & sms)



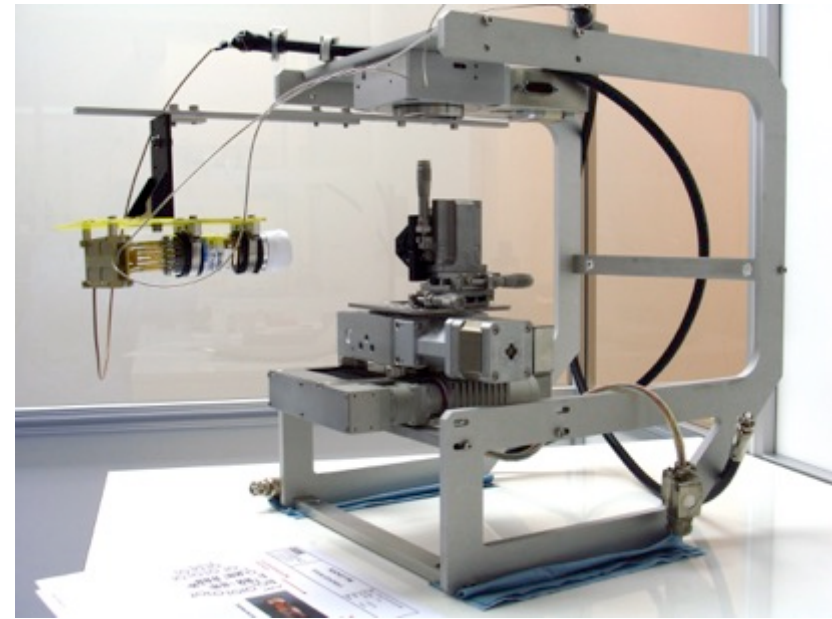
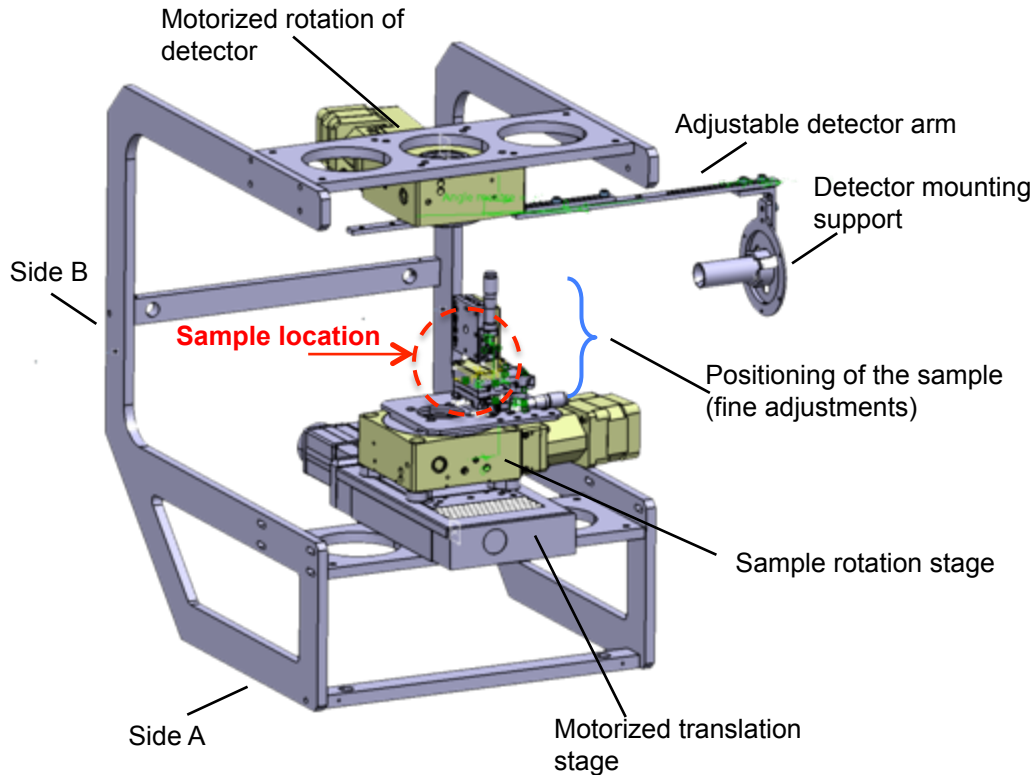
Banc optique VUV



CALIBRATION: OGSE

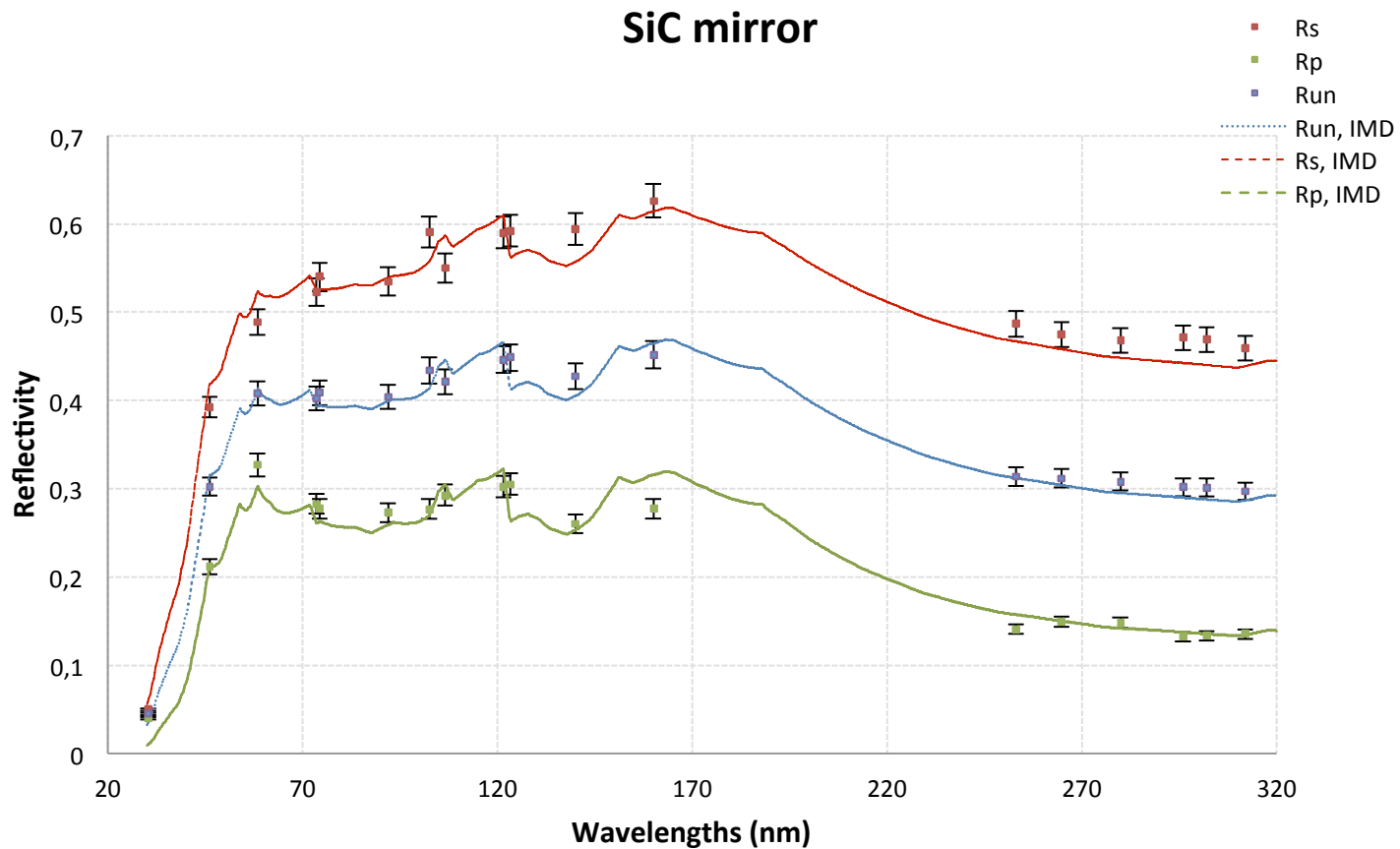


VUV optical bench – schematic view



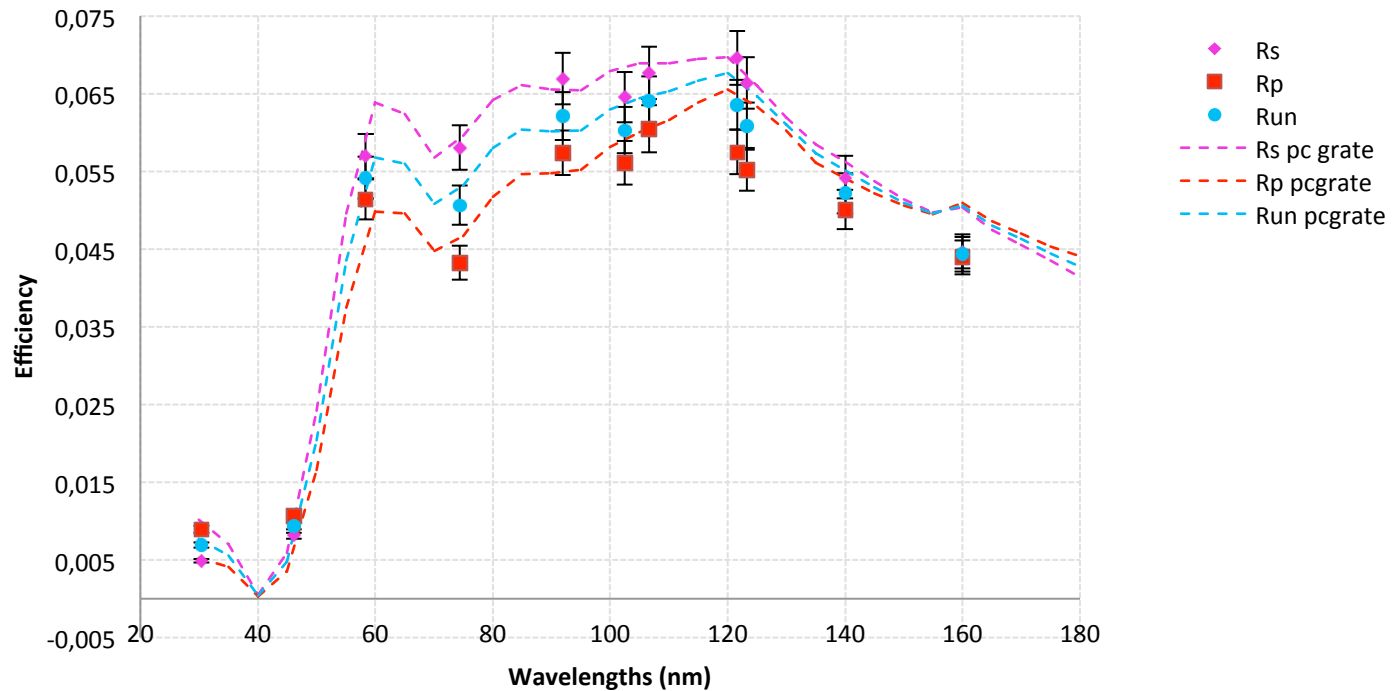
VUV Reflectometer

Mirror reflectivity

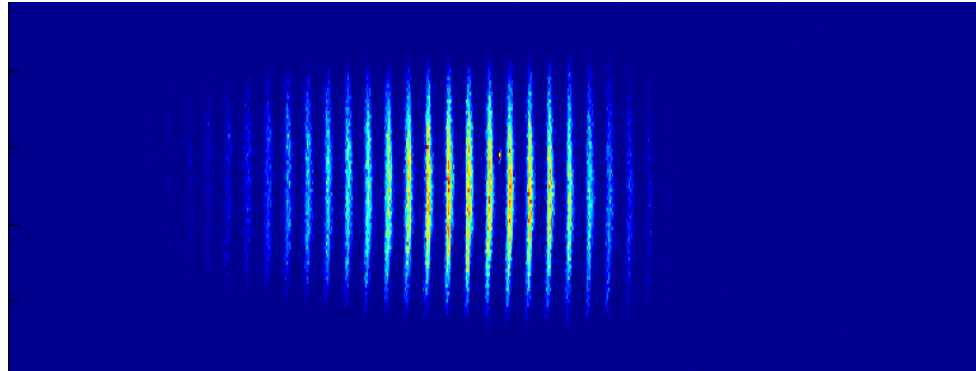




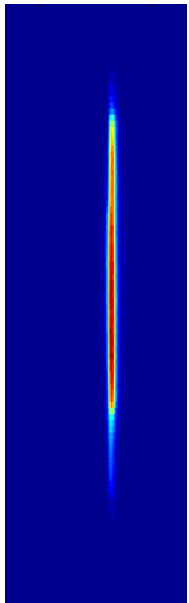
EUV Grating efficiency



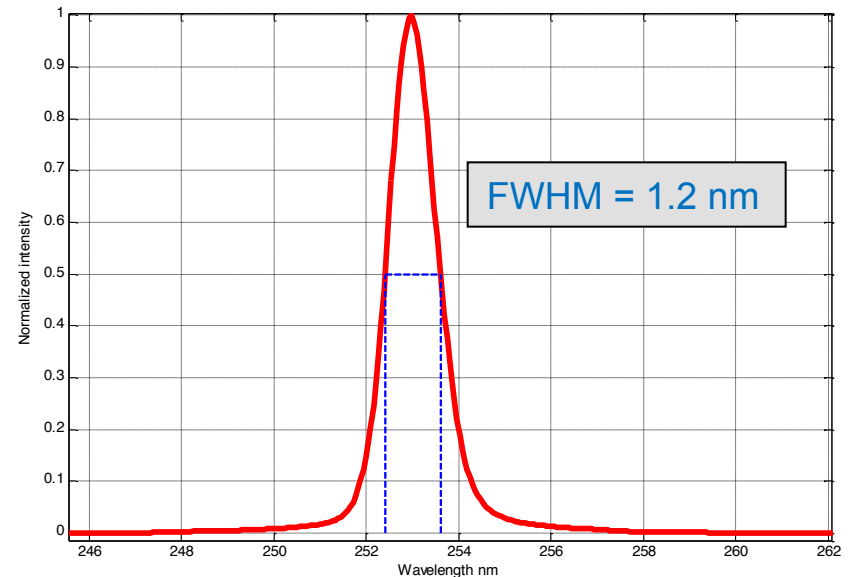
Spectral calibration – FUV channel (145 – 315 nm)



Spectral scanning from 180 nm to 320 nm



Hg line @ 253.6 nm



FWHM = 1.2 nm

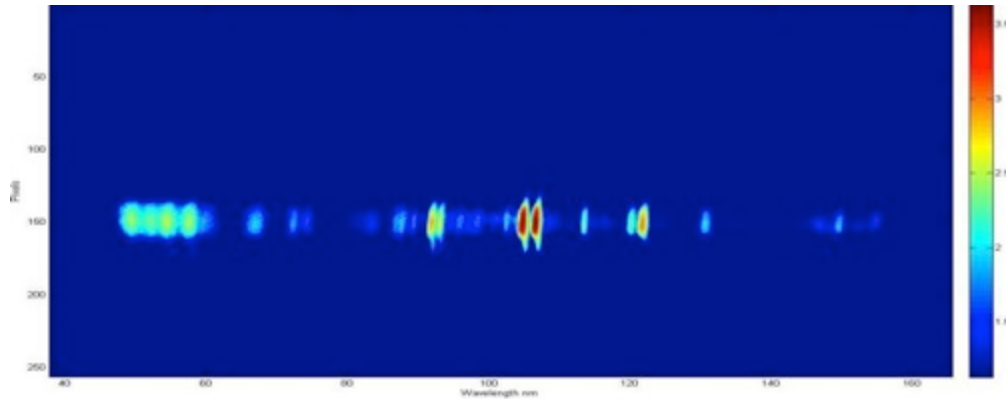
Hg line at 253.6 nm (Integration time = 10 min).

FWHM @ 253.6 nm



CALIBRATION: some results

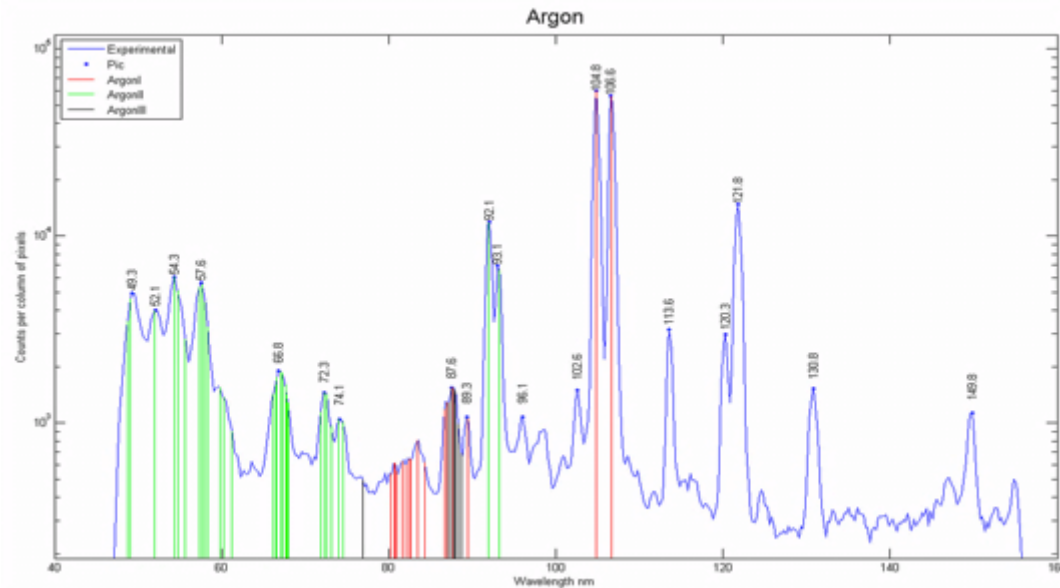
Spectral calibration - EUV channel (55 – 155 nm)



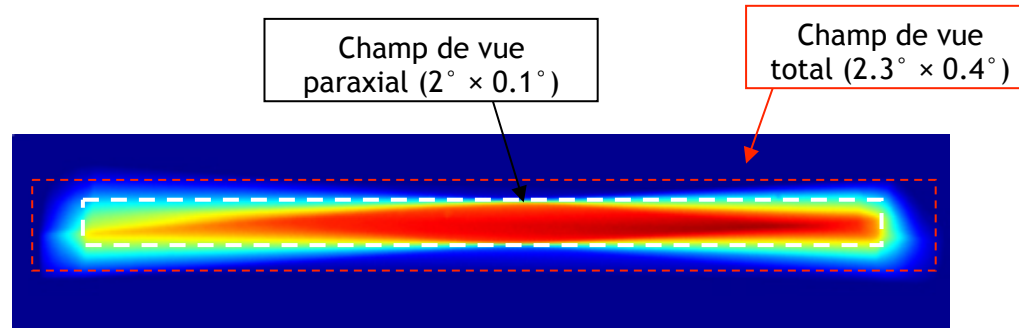
*EUV detector Image for Argon gas: HV = -3436 V, this image corresponds to a cumulated integration time of 10 min.
Count rate is about 1500 counts per second. (Levels are in \log_{10} -scale)*

*EUV spectrum of Argon gas
And NIST lines assignment (Levels are in \log_{10} -scale)*

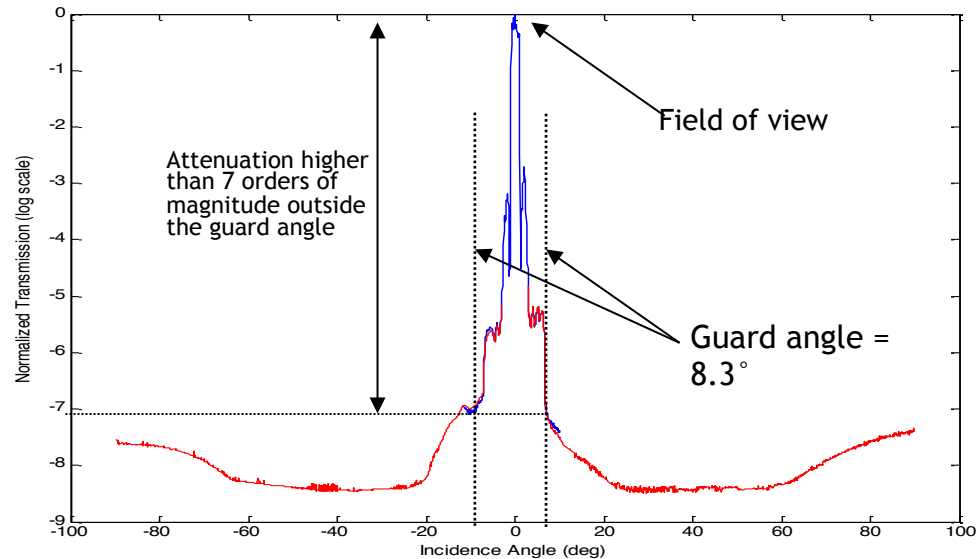
FWHM ~ 0.8 nm



Field of view

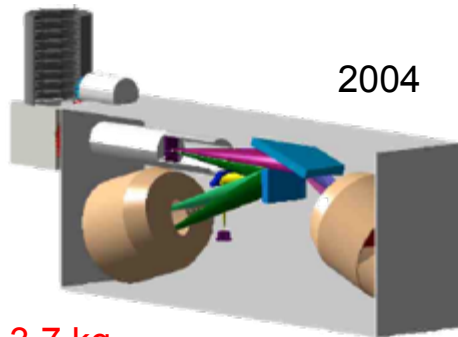


Baffle attenuation

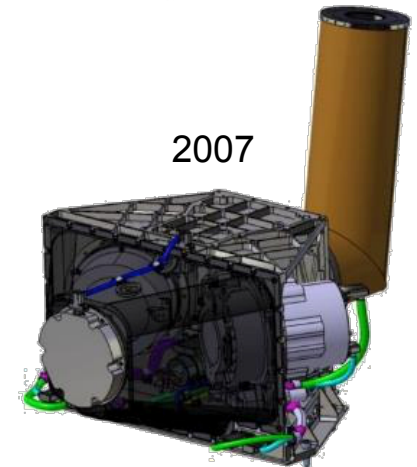
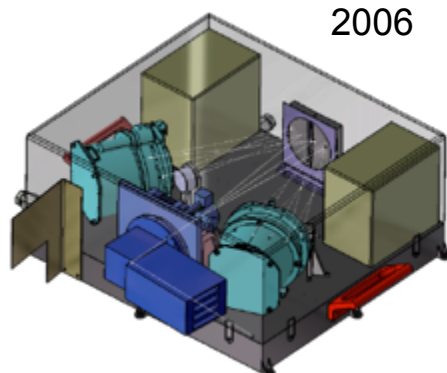
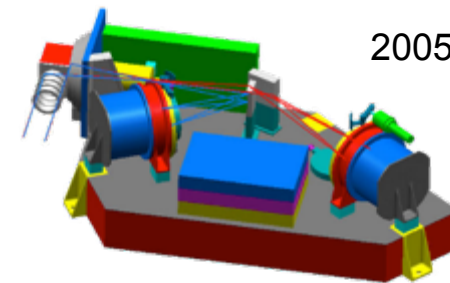


Maturity of the concept

- Maturity level at selection: unproven feasibility and unrealistic budget.
- More than 3 years spent doing prototyping to ensure feasibility in parallel to the overall design
- 100% increase in mass between proposal and Flight Model.



Selection at 3.7 kg



Final design at 7.5 kg

Technical challenges

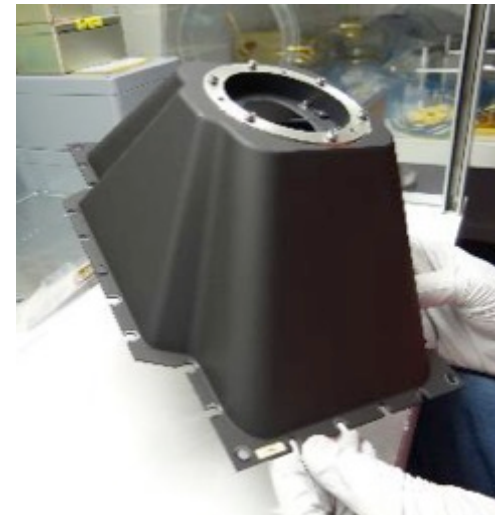
Many subsystems have proved to be early industrial achievements: Entrance baffle, SiC mirror, diffraction gratings, Al Structure, carbon cover...).

- Aluminium structure and carbon cover

- One-piece structure machined from solid (40kg → 830g), Ceral SPC7022 - 200h of machining → Corrosion problems of the treatment, 20k€/piece.
- Choice of a mechanical architecture minimizing the final mass, but dependent on all interface subsystems, including co-PI supplies => AIT constraints.
- Carbon cover with strong geometric constraints (Gratings support, therefore subject to the constraints of the optical dimensioning)



Main structure



Carbon cover

- Diffraction gratings

- Aluminium substrate Vs. Glass: SPICAM –SPICAV heritage to make mechanical interfaces easier, BUT :

- It required 2 different companies: one for the Al substrate and the other one for the grating recording (Horiba Jobin-Yvon): Too many intermediaries, difficulty to go back to the source of a possible problem.
- At reception of the substrate Horiba JY had difficulties in cleaning and surface preparation: change of cleaning products to meet RoHS standards. Surface of substrate too well polished ($<5\mu\text{m}$)=> grip problem !
- Alodine treatment (residual on the edges of surfaces) was also questioned for the grip of the different grating layers
- Manufacturing replicas on aluminium is more difficult than on glass.

- Recording area Vs. Total area.

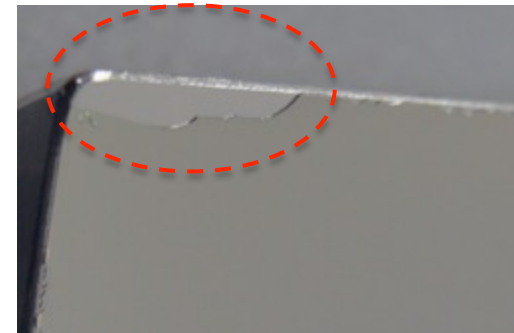
- In order to maximize the useful area: Grating etching up to 1mm from the edge
=> Too difficult to satisfy (usually 3 to 4 mm for the edges).

- Mounting interfaces

- The fixing tabs (connected to the substrate) interfered with the with the tools for manufacturing the substrates.



⇒ **Separation of the coating**



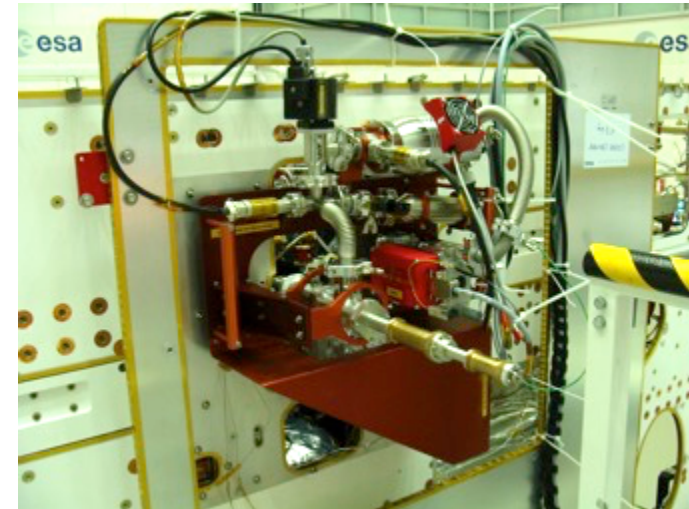
Separation of the coating on the FUV grating – Qualification model

- Mirror

- Originally built-in foot to make mechanical interfaces easier BUT:
 - Too difficult to machine (ceramic => very brittle, small piece => interface with machine tools difficult)
 - Finally bonding on titanium base (3M 2216 glue).
- Roughness < 0.7 nm RMS (to minimise straylight) :
 - Feasible but with an extremely high cost + long machining time.
- Convergence Shape Error Vs. Roughness
 - Difficult to reach => required a long iterative process between diamond polishing and ion etching

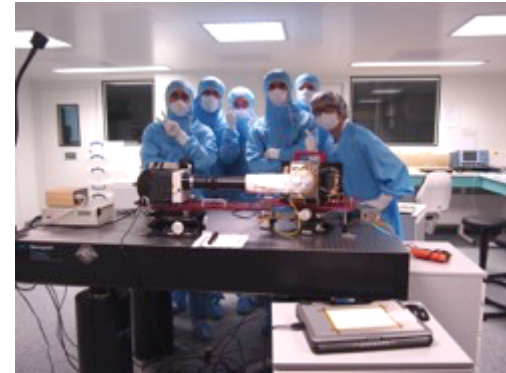
- EUV detector

- Requires dedicated pumping system until launch
 - ATEX certification (Explosive Atmosphere).
 - Training of spacecraft AIT staff
 - Constrains during AIT phase on spacecraft.
- Window opening system non reversible:
 - Requires an additional, complex closing system during the vacuum calibration phases of the instrument.



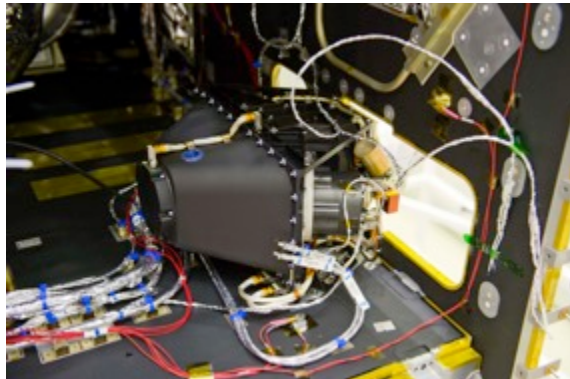
Pumping system integrated on the MPO spacecraft

- The human and technical extraordinary adventure
 - Flight Model delivered on time.
 - An instrument reaching the expected performances.
 - A fantastic human adventure with a lot of international collaborations.
 - A capitalized experience feedback for the future UV projects...



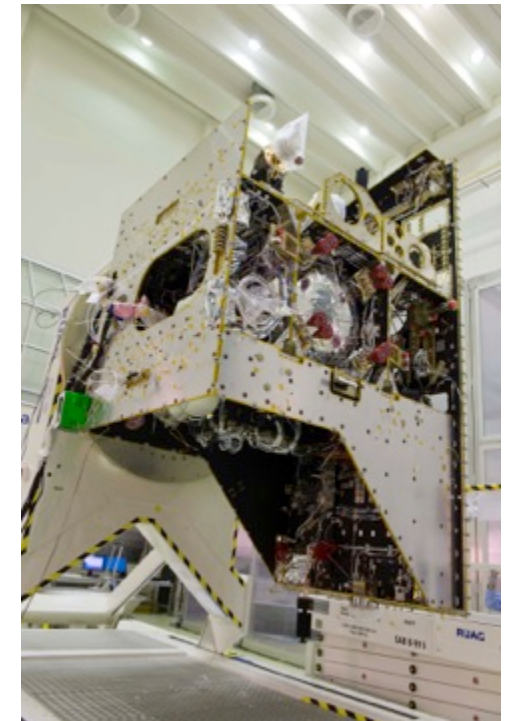
Crédits photo ESA

PHEBUS Qualification and Flight Models



Crédits photo ESA

PHEBUS onboard MPO



Crédits photo ESA

MPO Spacecraft



Thank you



Bibliography

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